## AMENDMENTS TO THE CLAIMS

- 1. (Currently Amended) A device comprising: i) a first microchannel; and ii) a second microchannel, said first and second microchannels etched in a substrate so as to be intersecting[[,]]; and iii) a meltable material disposed within said first microchannel, said meltable material comprising solder; and iv) a heating element associated with said meltable material.
- 2. (Canceled)
- 3. (Original) The device of Claim 1, wherein said substrate is selected from the group consisting of glass and silicon.
- 4. (Canceled)
- 5. (Original) The device of Claim 1, wherein said solder comprises a eutectic alloy of tin and lead.
- 6. (Original) The device of Claim 5, wherein said alloy comprises 60:40 Sn:Pb.
- 7. (Currently Amended) The device of Claim [[4]] 5, wherein said solder comprises 40:60 Sn:Pb.
- 8. (Canceled)
- 9. (Original) The device of Claim 1, further comprising a diaphragm positioned such that it is capable of touching said meltable material when extended.
- 10. (Currently Amended) A method, comprising:
  - a) providing a device comprising: i) a first microchannel; and ii) a second microchannel, said first and second microchannels etched in a substrate so as to be

intersecting[[,]]; iii) a meltable material disposed within said first microchannel, said meltable material comprising solder, said meltable material associated with a heating element; and

- b) heating said meltable material with said heating element such that said meltable material at least partially liquifies to create a liquified material and such that said substrate is not damaged, wherein said liquified material moves into said second microchannel.
- 11. (Original) The method of Claim 10, further comprising c) allowing said meltable material to cool.
- 12. (Canceled)
- 13. (Original) The method of Claim 10, wherein said substrate is selected from the group consisting of silicon and glass.
- 14. (Canceled)
- 15. (Currently Amended) The method of Claim [[14]] <u>10</u>, wherein said solder comprises a eutectic alloy of tin and lead.
- 16. (Original) The method of Claim 15, wherein said alloy comprises 40:60 Sn:Pb.
- 17 21. (Canceled)
- 22. (New) A device comprising: i) a first microchannel; ii) a second microchannel, said first and second microchannels etched in a substrate so as to be intersecting; iii) a meltable material disposed within said first microchannel; iv) a diaphragm configured such that said diaphragm, when extended, touches said meltable material.
- 23. (New) The device of Claim 22, wherein said meltable material comprises solder.

- 24. (New) The device of Claim 23, wherein said solder comprises a eutectic alloy of tin and lead.
- 25. (New) The device of Claim 24, wherein said alloy comprises 40:60 Sn:Pb.
- 26. (New) The device of Claim 22, wherein said substrate is selected from the group consisting of silicon and glass.
- 27. (New) The device of Claim 22, further comprising a heating element associated with said meltable material.